

Abstract of the Disclosure

A defect source identifier that provides information used to identify a source of a defect on a substrate, which defect source identifier includes a LotRoute database generation process and a LotRoute database access process, wherein the

5 LotRoute database generation process includes a software application that runs on a server and that, in response to user input, defines a wafer route including wafer route information, and associates the wafer route with any one of a number of entities; and the LotRoute database process includes a software application that runs on the server and that, in response to input from the defect source identifier, retrieves the wafer route

10 information using an identifier of one of the entities.